

SEMICONDUCTOR CIRCULAR AND RADIAL FLOW COOLER

ABSTRACT OF THE DISCLOSURE

A heat exchanger with a circular fluid chamber, configured to distribute cooling fluid flow from the center of the chamber to the periphery of the chamber. Fins are disposed within the chamber to direct the flow in a generally radial or spiral pattern. There is an annular recess with varying cross sectional area in the overhead wall of the chamber to equalize pressure drop from the center of the chamber to an outlet aperture from any initial radial flow path. The configuration of the exchanger imparts a rotational flow velocity to the fluid when it reaches the outer perimeter or annular wall of the chamber. The rotational flow reduces back pressure against the radial or spiral flow being directed to the periphery of the circular chamber. The inlet flow is introduced from the overhead wall and impinges on the center of the bottom plate of the chamber. The impact creates turbulence in the fluid which increases heat overall heat transfer coefficient of the exchanger. The exchanger is rotatably mounted in a clamp plate.